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## APJ ABDUL KALAM TECHNOLOGICAL UNIVERSITY

Sixth Semester B.Tech Degree (S,FE) Examination May 2022 (2015 Scheme

# Course Code: EC304

## Course Name: VLSI

Max. Marks: 100

#### **Duration: 3 Hours**

## PART A Answer any two full questions, each carries 15 marks

Marks

- a) With neat sketches explain Czochralski process of crystal growth. Comment on (8)
  the quality of the crystals grown through this technique.
  - b) Discuss the oxidation technique employed in growing gate oxide and field oxide (2) in MOSFETs. Justify your choice
  - c) A dry oxidation process designed to grow 120 nm of oxide on silicon wafers at (5) 900°C. What is the time required to obtain this thickness? What is the time if steam can be used instead?

 $(B/A = 2.63 \times 10^{-6} \,\mu\text{m/sec}, B = 1.11 \times 10^{-6} \,\mu\text{m}^2/\text{sec}$  for dry oxidation and

 $B/A = 4.2 \times 10^{-5} \text{ }\mu\text{m/sec}, B = 4.32 \times 10^{-6} \text{ }\mu\text{m}^2\text{/sec}$  for wet oxidation. Assume a fictitious initial thickness of 0.020  $\mu\text{m}$  for dry oxidation.)

- 2 a) Compare two step thermal diffusion and ion implantation techniques with their (10) relative merits and demerits. Draw the doping profiles in each case and explain with necessary modelling equations.
  - b) Explain the technique of fabricating resistors and capacitors in integrated circuits. (5)
- 3 a) With sketches, explain the fabrication process flow for realizing a CMOS inverter (10)
  in N-well technology. Draw the mask for each step assuming positive photo resist.
  - b) Define the following terms in the context of photolithography and explain how (5) these terms are related to the pattern which is transferred on to silicon.

i) Resolution ii) Depth of focus iii) Contrast

## PART B Answer any two full questions, each carries 15 marks

4 a) Draw the DC transfer characteristics of CMOS inverter. Derive an expression for (10) the switching threshold of the device and explain how the β ratios of the devices affects the transfer characteristics,

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	b)	What are the sources of static power dissipation in CMOS inverter? (						
	c)	Realize the logic function in complementary CMOS logic.						
	$Y = \overline{A + C(B + D)}$							
5	a) Draw the schematic, stick diagram and layout of two input NOR gates.							(10)
	b)	List the factors on which the delay of CMOS inverter depend? Discuss methods to						
		reduce this delay.						
6	a)	Comment on the use of level restorer in pass transistor logic? With a circuit						
	diagram and explain the operation.							
	b)	Discuss transmission gate logic? State the advantages over pass transistor logic?						
¥.	c)	Implement 2:1 mux using transmission gates. Implement 4:1 mux using three 2:1						
		muxs. Explain the operation of the circuit.						
PART C								
7	7 a) Draw the circuit of 6T SRAM cell Explain its read and write one							(10)
		Comment on the	sizing c	sizing constraints of the transistors				
	<b>b</b> )	) Design a 4x4 NAND ROM to store the data						
	,	Address	0	1	2	3		
		Data	1010	1100	0100	1111		
	c)	Design a PLA w	ith outpu	its the	sum of th	e follo	ving minterms	(5)
	•)	F1 = m1 + m6, $F2 = m5 + m6 + m7$ , $F3 = m3 + m2 + m4 + m7$						(5)
8	a)	Draw and explain the architecture of CLB based FPGA (10						
•	b)	Design a 16-hit linear carry select adder Mark the critical nath and calculate its (1						
	-)	worst-case delay						
9	a)	a) Design a circuit to multiply two 4-bit binary numbers $\Delta_2 \Delta_2 \Delta_3 \Delta_4 \Delta_6$ and $B_2 B_2 B_3 B_4$						(10)
	b)	Design a 32-hit carry hypass adder using 4-hit carry hypass technique. Mark th						
5	-)	critical nath and calculate its worst-case delay						
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